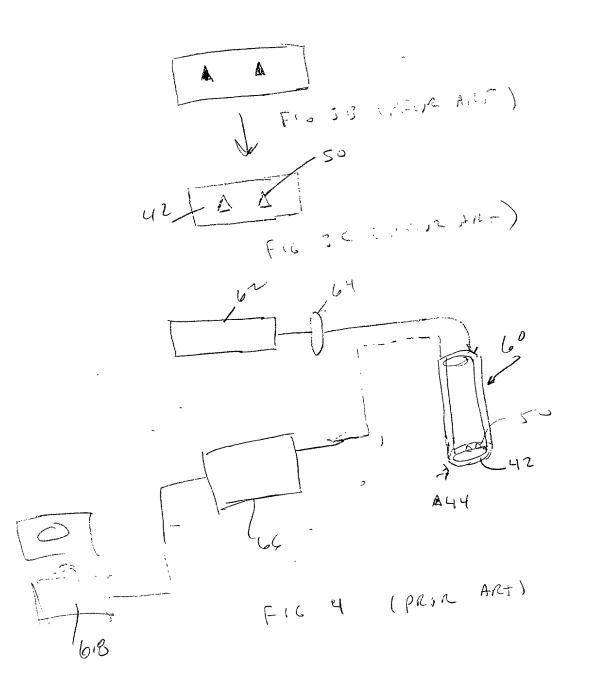
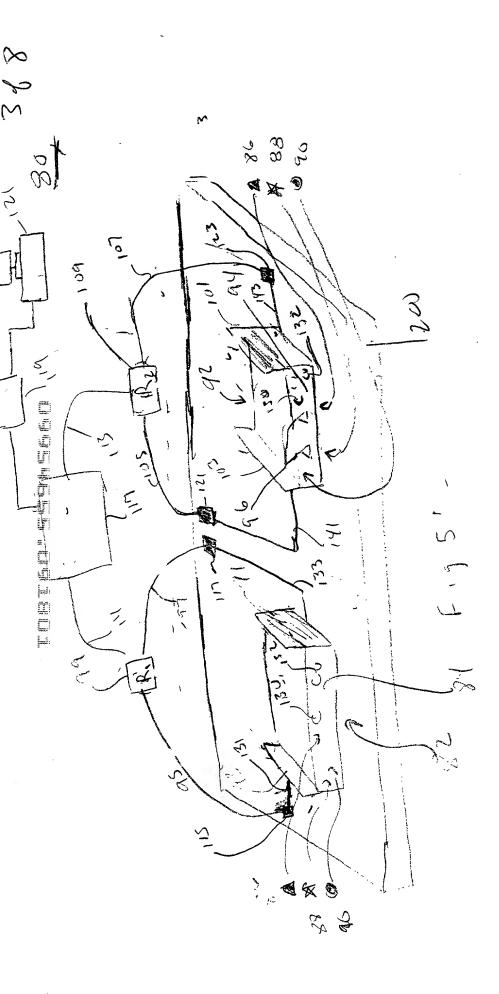


Fig 3 A (Parior ART)

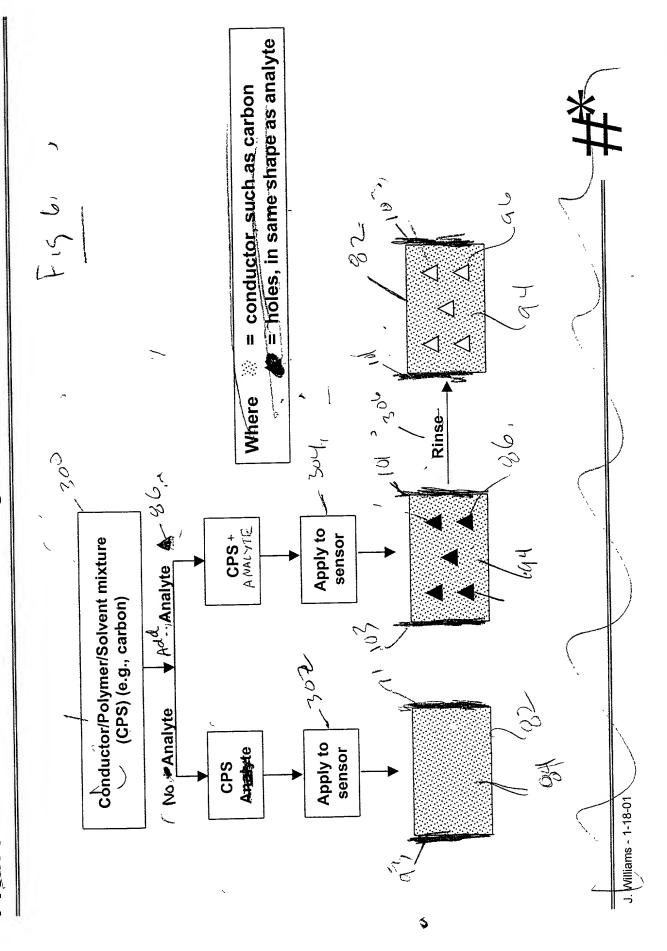




\*

8 9 h

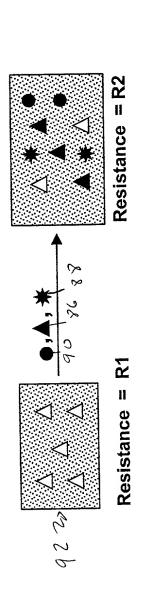
Flowchart for Molecular Recognition Paired Sensors Fabrication

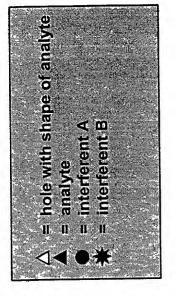


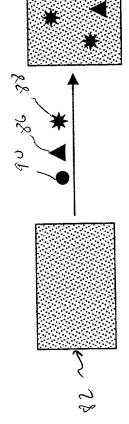
## 5 9 8

## Resistive Detection Exposure of Molecular Recognition Paired Sensors

1) Add mixture (gas or liquid) containing analyte plus interferents to resistance detector







Resistance = R4

Resistance = R3

there are no cavities, and this absorbed chemical leads to resistance increase. See sheet aborbed into cavities and does not contribute to resistance. Resistance only increases if 2) Measure R1, R2, R3, R4. At low concentrations of analyte of interest ∆ analyte is of equations.

3) Calculate R▲ resistance change due to analyte of interest from R1, R2, R3, R4

**Draper Laboratory Proprietary** 



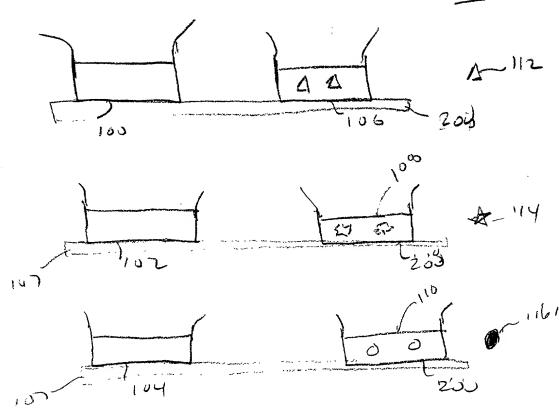


Fig. 8

## Resistive Network for Exposure of Molecular Recognition Sensors

 $_{\iota^{(L)}}$  polymer with range of cavities from none (top) to high (5%) concentration (bottom) for two different analytes  $\sigma_{\ell} \tau$  Array of resistive sensors consisting of Contacts for electrical leads from resistors for connection to test Metal contact pads for electrical contact to polymer <sub>عمر</sub> equipment Seramic substrate こうべん 3 244 246 1248 120/ 233 5827 182. స్ట 230/283 202 800 900

Draper Laboratory-Proprietary

J. Williams - 1-18-01-Modified C. E. Dubé 2/19/01

tormins a resistive sensitive

polymer film to form
a molecular imprinted
resistive seasor

402

404

detecting a change in resistive sensor and movie char imprimed resistive sensor

Subtracting the change in resistance of molecular imprinted consor from the change in resistance of the resistance of th

406

Fig (0